IPW

00862.023399

## **PATENT APPLICATION**

IN THE UNITED STATES P	ATENT AND TRADEMARK OFFICE
In re Application of:	)
-	: Examiner: Not Yet Assigned
KAZUHITO TAKANASHI ET AL.	)
Amplication No. 10/754 521	: Group Art Unit: 1746
Application No.: 10/754,531	)
Filed: January 12, 2004	;
,,	•
For: ETCHING METHOD	) May 12, 2004
Commissioner for Patents P.O. Box 1450	

## **PRELIMINARY AMENDMENT**

Sir:

Alexandria, VA 22313-1450

## A. Introductory Comments

Prior to conducting the examination on the merits, please amend the above-captioned application as follows and consider the following remarks.